

Development of Atomic Layer Etching process dedicated to diamond electronic devices

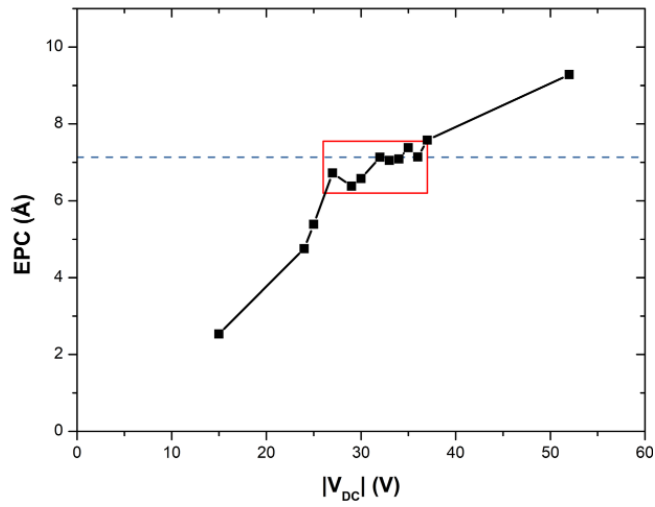


Figure 1 –Etching rate Per Cycle for the ALE process, vs self-bias voltage.